



Docket No. 740756-945

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#62  
Ineda  
11/4/02

In re Patent Application of: )

Hisato SHINOHARA et al. )

Serial No. 08/169,127 )

Filed: 12/20/1993 )

For: METHOD AND SYSTEM OF LASER PROCESSING )

Examiner: M. Padgett

Group Art Unit: 1762

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
Washington, DC 20231

RECEIVED  
NOV 04 2002  
TC 1700

Sir:

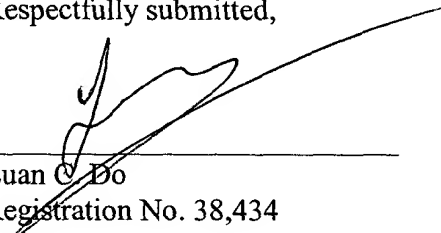
In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the reference listed on the attached Form PTO-1449 be made of record in the above-identified application.

This Information Disclosure Statement is presented in order to correct errors in the Information Disclosure Statement filed on September 5, 2002. Notably, the citation U.S. Patent No. 5,423,112 to Hong should instead read U.S. Patent No. 5,423,122 to Chae, the author "Misura et al." of the article entitled "High-Performance Low-Temperature Poly-Si TFTs for LCD", IEDM 87, pp. 436-439, (January 1987) should instead recite "Mimura et al." A full copy of U.S. Patent No. 5,423,122 is submitted for consideration by the Examiner. Note further that a full English translation of the citation JP 63-195149 is also submitted in lieu of the English abstract that was previously filed.

Accordingly, Applicant respectfully requests that the Examiner not consider the previously noted citations of the September 5, 2002 IDS by drawing a line therethrough and instead consider the correct citations listed on the attached Form PTO 1449.

The Commissioner is hereby authorized to charge fees under 37 C.F.R. §§1.16, 1.17, 1.20(a), 1.20(b), 1.20(c), and 1.20(d) (except the Issue Fee) which may be required now or hereafter, or credit any overpayment to Deposit Account No. 19-2380 (740756-945).

Respectfully submitted,



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